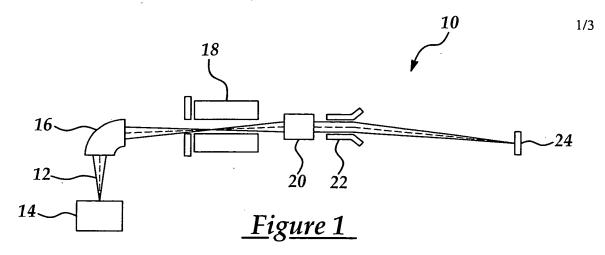
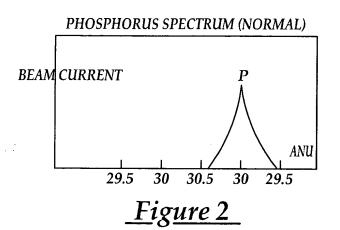
Inventor: CHEN-CHUNG LI

Serial No.: To Be Assigned Filed: Herewith

For: ION IMPLANTER AND METHOD OF PREVENTING UNDESIRABLE IONS FROM IMPLANTING A

TARGET WAFER
Attorney Doc. No.: 67,200-1218





PHOSPHORUS SPECTRUM (CONTAMINATE)

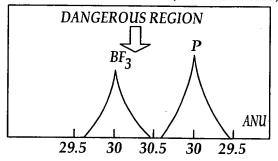


Figure 3

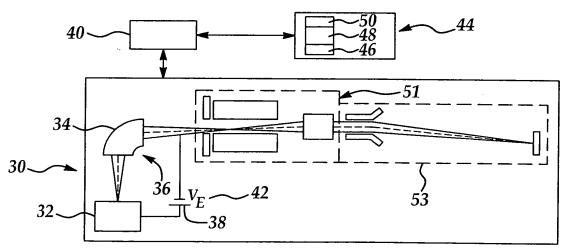
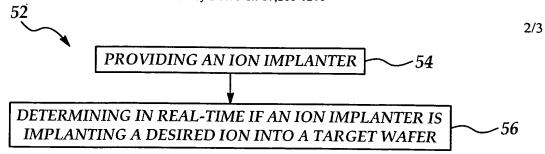


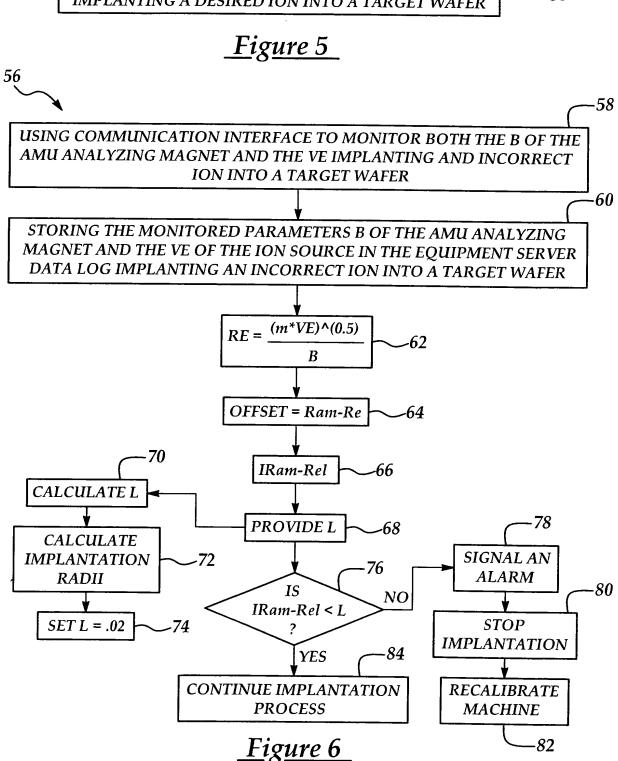
Figure 4

Inventor: CHEN-CHUNG LI Serial No.: To Be Assigned Filed: Herewith

For: ION IMPLANTER AND METHOD OF PREVENTING UNDESIRABLE IONS FROM IMPLANTING A

TARGET WAFER Attorney Doc. No.: 67,200-1218





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For: ION IMPLANTER AND METHOD OF PREVENTING UNDESIRABLE IONS FROM IMPLANTING A

TARGET WAFER

Attorney Doc. No.: 67,200-1218

3/3

	B ₁₁					P ₁₁					BF ₂₍₄₉₎				
AMU (in)	10	10.5	11	11.5	12	30	30.5	31	31.5	32	48	48.5	49	49.5	50
В	3.4	3.5	3.6	3.7	6.1	5.8	6	6	6.1	6.1	7.5	7.5	7.5	7.6	7.6
	18.22	19.33	20.39	21.50	56.80	18.57	19.94	20.00	20.64	20.61	19.80	19.78	19.87	20.49	20.47
R	3.97	4.07	4.16	4.25	4.28	4 07	411	416	118	4 21	111	112	116	110	121

<u>Figure 7</u>

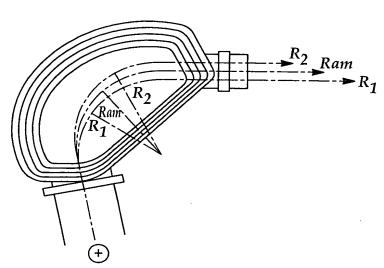


Figure 8